

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET
NO. 35523US1SERIAL NO.
10/825,504INFORMATION DISCLOSURE CITATION
BY APPLICANT

APPLICANT: Volker Derflinger et al.

FILING DATE:
April 15, 2004GROUP ART UNIT:
3722

U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Date	Name	Class	Subclass	Filing Date if Appropriate
	A						
	B						
	C						
	D						
	E						
	F						
	G						

FOREIGN PATENT DOCUMENTS

		Document No.	Date	Country	Class	Subclass	Translation
	H	1 186 681 A1	8/2001	EP			Cited in Spec.
	I	09-041127	8/1995	JP			Cited in Spec.
	J						
	K						

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

	R	Thin films (Proc. 4 in. Sympos. Trends & New Applications of Thin Films 1993) DGM Info. Sges., Oberursel 1993, p 73.
	S	Surface & Coatings Technology vol. 165, 2 (2003) p. 163-167. Oxidation Resistance of Cr _{1-x} Al _x N and Ti _{1-x} Al _x N films.
	T	Surface & Coating Technology vol. 163-164 (2003) p. 57-61. High-Temperature Oxidation Resistance of Cr _{1-x} Al _x N Thin Films Deposited by Reactive Magnetron Sputtering.
	U	J. Vac. Sci. Technol. A 20(2), Mar/Apr 2002, p. 569-571. Microhardness and Lattice Parameter of Cr _{1-x} Al _x N Films.
	V	Surface & Coating Technology, vol. 163-164 (2003) p. 546-551. Abrasive Wear Tsting of DLC Coatings deposited on plane and Cylindrical Parts.
	W	Tribologie-Fachtagung 2000, moers: Ges. F. Tribol. 2002, ISBN 3-00-003404-8, Investigations of Mechanical and Tribological Properties of CrAlN + C Thin Coatings Deposited on Cutting Tools.

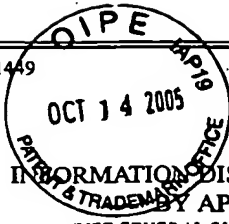
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Form PTO-1449 <div style="text-align: center;">  </div>		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. 35523US1		SERIAL NO. 10/825,504	
INFORMATION DISCLOSURE CITATION BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)				APPLICANT: Volker Derflinger et al.		FILING DATE: April 15, 2004	
		GROUP ART UNIT: 3722					

U.S. PATENT DOCUMENTS							
Examiner Initial	Document No.	Date	Name	Class	Subclass	Filing Date If Appropriate	
A	A	2003/0035894 A1	02/2003	Derflinger et al.			
	B						
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FOREIGN PATENT DOCUMENTS							
Document No.	Date	Country	Class	Subclass	Translation		
I	10-25566	01/1998	Japan				English Abstract
J	9-41127	02/1997	Japan				English Abstract
K	1 422 311 A2	11/2003	Europe				English Text
L	1 422 311 A3	11/2003	Europe				English Abstract

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)	
M	F. Sanchette, A. Billard, C. Frantz, "Mechanically reinforced and corrosion-resistant sputtered amorphous aluminium alloy-coatings", Surface and Coatings Technology 98 (1998), pages 1162-1168.
N	J. Vetter, E. Lugscheider, S.S. Guerreiro, "(Cr:Al) N Coatings deposited by the cathode vacuum arc evaporation", Surface and Coatings Technology 98 (1998), pages 1233-1239.
O	Clemens Kunisch, Ronald Loos, Michael Stuber and Sven Ulrich, "Thermodynamic modeling of Al-Cr-N thin film systems grown by PVD", 1999, pages 847-852.
P	Y. Ide, T. Nakamura and K. Kishitake, "Formation of Al-Cr-N films by a DC reactive sputtering method and evaluation of their properties", 2000, pages 291-296.

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